

FORM PTO-1449 (Modified)		US DEPARTMENT OF COMMERCE		Docket No. 050623.245	Application No. 10/623,908
US Patent and Trademark Office				Applicant Paul John Kawula	
INFORMATION DISCLOSURE CITATION in an Application (Use several sheets if necessary)				Filing Date July 21, 2003	Group Art Unit 3738
U.S. PATENT DOCUMENTS					
Examiner Initial	Ref. No.	Document Number	Date of Patent	Name	Class Subclass Filing Date if Appropriate
	A1				
U.S. PATENT APPLICATIONS					
Examiner Initial	Ref. No.	Document Number	Date of Patent	Name	Class Subclass Filing Date if Appropriate
	A2				
FOREIGN PATENT DOCUMENTS					
Examiner Initial	Ref. No.	Document Number	Date of Publication	Country	Class Subclass Translation Yes No
	B1	WO 2005/113856	12/1/05	WIPO	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)					
	C1	Aluminium oxide, Wikipedia, the free encyclopedia, downloaded from http://en.wikipedia.org/wiki/Alumina , June 12, 2007, 5 pgs.			
	C2	Ceramic, Wikipedia, the free encyclopedia, downloaded from http://en.wikipedia.org/wiki/Ceramic , June 12, 2007, 8 pgs.			
	C3	"Ceramics-a.k.a. "burnt stuff"- contain at least 1 metal oxide", CCMR-Ask A Scientist, downloaded from http://www.ccmr.cornell.edu/education/ask/index.html?quid=1088 , June 12, 2007, 2 pgs.,			
	C4	Chen, "New Coating Process Enables Higher-Efficiency Engines", Berkeley Lab Research News, 1996, 3 pgs.			
	C5	Chen et al., "Al ₂ O ₃ - TiO ₂ composite oxide films on etched aluminum foil by gydrolysis precipitation and anodizing", J. Mater. Sci. 41, pp. 569-571 (2006).			
	C6	Ciridon et al., "Plasma Deposition", Biomaterials Tutorial, Univ. of Washington Engineered Biomaterials, 2004, 3 pgs.			
	C7	Holcombe Jr. et al., "Oxygen sensitive, refractory oxide composition", downloaded from http://www.patentdigi.com/liquid_crystal/oxygen_sensitive_refractory_oxide_composition , June 12, 2007, 7 pgs.			
	C8	Kern et al., "Electrolytic Deposition of Valve Metal Oxide Thin Films as Interference Coatings on Biomedical Implants", EU Cells and Materials vol. 10, Suppl. 1, 2005, pg. 25.			
	C9	"Plasma Processing and Low Energy Plasma Science" The National Academies Press, downloaded from http://books.nap.edu/openbook.php?record_id , June 12, 2007, 5 pgs.			
	C10	Zhitomirsky, "Ceramic Films Using Cathodic Electrodeposition", downloaded from http://www.tms.org/pubs/journals/JOM/0001/Zhitomirsky/ , June 12, 2007, 11 pgs.			
	C11	Wood et al., "Implantation and deposition of adherent metal-oxide ceramic", IEEE Xplore, downloaded from http://ieeexplore.ieee.org/xpl/freeabs_all.jsp?arnumber=533482 , June 12, 2007, 1 pg.			
EXAMINER			DATE CONSIDERED		
EXAMINER: Initial if references considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.					